



1746/8

THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Toshihito Tsuga, et al.

Docket No: TI-31620

Serial No: 10/085,753

Conf. No: 8409

Examiner: Michail Kornakov

Art Unit: 1746

Filed: 02/28/2002

For: METHOD AND DEVICE FOR REMOVING PARTICLES ON SEMICONDUCTOR WAFERS

AMENDMENT UNDER 37 C.F.R. § 1.111

RECEIVED


DEC 11 2003

TC 1700

Commissioner For Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**MAILING CERTIFICATE UNDER 37 C.F.R. §1.8(a)**

I hereby certify that the above correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on 12-3-03.

  
Ann Trent

Dear Sir:

Responsive to the Office Action mailed October 27, 2003, in connection with the above identified application, Applicants respectfully submit the following amendments and remarks.